

Docket Number: 081468-0307087
Client Reference: P-0395.010-US

JPW
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re the Application of

SIMON et al.

Group Art Unit: 1753

Application No.: 10/724,402

Examiner: Unassigned

Filed: December 1, 2003

Confirmation No.: 8896

For: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

February 2, 2005

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. 1.56, the attention of the Patent and Trademark Office is hereby directed to the following U.S. patent application(s):

Examiner's Initials	First Inventor	Application No.	Filing Date	Enclosed
	SUWA et al. (Reissue Application of U.S. Patent No. 6,191,429 B1)	10/367,910	02/19/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input type="checkbox"/> Other: stamped receipt card

*The Examiner's initials adjacent a citation indicates he/she has considered the cited application relative to the subject application.

It is respectfully requested that the above-identified application and the art cited therein during examination be expressly considered during the prosecution of this application and be made of record in this application. The identification of the above U.S. patent application is not to be construed as a waiver of secrecy as to that application now or upon issuance of the present application as a patent.

PLEASE DO NOT PRINT the above information on the patent which results from this application.

Consideration of the listed application is earnestly solicited since unpublished patent applications are contemplated as IDS material; see the exception in Rule 98(a)(2)(iii) and note the penultimate sentence of MPEP 609.

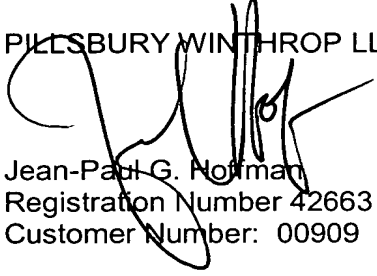
Further, in keeping with MPEP 609, subsec. C(2), 2nd para., line 10 to end of the paragraph (especially note lines 18-25) **PLEASE RETURN A COPY OF THIS LETTER** with the Examiner's initials adjacent the above listing so that applicant will know that the listed application has been considered as required by PTO policy.

Secondly, please consider each document which is listed on the attached Form PTO-1449 and return a copy of that form with the Examiner's initials adjacent each citation, a copy of each document enclosed except for any U.S. patents and published patent applications. It is respectfully requested that these documents listed on the Form PTO-1449 be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

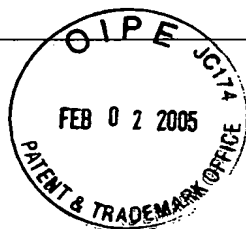
Respectfully Submitted,

PILLSBURY WINTHROP LLP



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Atty.
Dkt. No.

M#

Client Ref.

0307087

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: SIMON et al.

Appln. No.: 10/724,402

Filing Date: December 1, 2003

Date: February 2, 2005

Page

1

of

2

Examiner: Unknown

Group Art Unit: 1753

U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR 4,390,273	06/1983	LOEBACH et al.	355	125	
	BR 6,236,634 B1	05/2001	LEE et al.	369	112	
	CR 2002/0020821 A1	02/2002	VAN SANTEN et al.	250	492	
	DR 2004/0075895 A1	04/2004	LIN	359	380	
	ER 2004/0109237 A1	06/2004	EPPLÉ et al.			
	FR 2004/0119954	06/2004	KAWASHIMA et al.	355	30	
	GR 2004/0125351	07/2004	KRAUTSCHIK	355	53	
	HR					
	IR					
	JR					

FOREIGN PATENT DOCUMENTS

	Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
						Enclosed	No	Enclose	No
	KR WO 03/077037	09/2003	PCT	ROSTALSKI et al.		X			X
	LR DD 206 607	02/1984	GERMANY	WESTPHAL et al.			X		
	MR DD 221 563	04/1985	GERMANY	PFORR et al.			X		
	NR JP 11-176727	07/1999	JAPAN	SHIRAISHI		X			
	OR JP 2000-058436	02/2000	JAPAN	FUJISHIMA et al.		X			
	PR								
	QR								
	RR								
	SR								

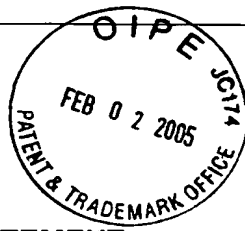
OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	TR	B. LIN, "The k_3 coefficient in nonparaxial NNA scaling equations for resolution, depth of focus, and immersion lithography, <i>J. Microlith., Microfab., Microsyst.</i> 1(1):7-12 (2002).			
	UR				
	VR				
	WR				
	XR				
	YR				
	ZR				

Examiner

Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.



Atty. Dkt. No.	M#	Client Ref.
	0307087	P-0395.010-US

**INFORMATION DISCLOSURE STATEMENT
 BY APPLICANT**

Applicant: SIMON et al.
Appln. No.: 10/724,402
Filing Date: December 1, 2003
Examiner: Unknown Group Art Unit: 1753

Date: February 2, 2005 Page 2 Of 2

U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
AAR						
BBR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
						Encl sed	No	Encl sed	No
	CCR	WO 2004/053950 A1	06/2004	PCT	OWA	X			
	DDR	WO 2004/053951 A1	06/2004	PCT	MAGOME et al.	X			
	EER	WO 2004/053952 A1	06/2004	PCT	MAGOME et al.	X			
	FFR	WO 2004/053953 A1	06/2004	PCT	NEI et al.	X			
	GGR	WO 2004/053954 A1	06/2004	PCT	NEI et al.	X			
	HHR	WO 2004/053955 A1	06/2004	PCT	HIRUKAWA et al.	X			
	IIR	WO 2004/053956 A1	06/2004	PCT	NAGASAKA et al.	X			
	JJR	WO 2004/053957 A1	06/2004	PCT	HIDAKA et al.	X			
	KKR	WO 2004/053958 A1	06/2004	PCT	MIZUTANI et al.	X			
	LLR	WO 2004/053959 A1	06/2004	PCT	SHIRAI	X			
	MMR	WO 2004/053596 A2	06/2004	PCT	GRAUPNER	X			
	NNR	WO 2004/055803 A1	07/2004	PCT	VAN SANTEN	X		X	
	OOR	WO 2004/057589 A1	07/2004	PCT	NEIJZEN et al.	X		X	
	PPR	WO 2004/057590 A1	07/2004	PCT	VAN SANTEN et al.	X		X	
	QQR	JP 2004-193252	07/2004	Japan	Not Available	X			

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

RRR				
SSR				
TTR				
UUR				
VVR				
WWR				
XXR				

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